

### **PATENT**

#31/H 3/4/3 Surles

#### N THE UNITED STATES PATENT AND TRADEMARK OFFICE

## In re Application of:

Pan et al.

Serial No.: 09/073,494

Filed: May 6, 1998

For: TECHNIQUE FOR ELIMINATION OF PITTING ON SILICON SUBSTRATE

**DURING GATE STACK ETCH** 

Confirmation No.: 9834

Examiner: H. Vu

Group Art Unit: 2811

**Attorney Docket No.: 2915.1US** 

(96-149.01)

#### **CERTIFICATE OF MAILING**

I hereby certify that this correspondence along with any attachments referred to or identified as being attached or enclosed is being deposited with the United States Postal Service as First Class Mail (under 37 C.F.R. § 1.8(a)) on the date of deposit shown below with sufficient postage and in an envelope addressed to the Commissioner for Patents, Washington, D.C. 20231.

February 19, 2003 Date of Deposit

Signature of registered practitioner or other person having reasonable basis to expect mailing to occur on date of deposit shown pursuant to 37 C.F.R. § 1.8(a)(1)(ii)

Amanda Holland

Typed/printed name of person whose signature is contained above

FEB 28 2003

# **AMENDMENT**

Commissioner for Patents Washington, D.C. 20231

Sir:

The following amendments and remarks are filed in response to the Examiner's remarks in the Office Action mailed October 24, 2002, the three-month shortened statutory period for response to which expired on January 24, 2003. Enclosed herewith is a Petition for One-Month Extension of Time and accompanying fee under 37 C.F.R. § 1.17(a)(1).